

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Prior Application: Y. KAWAMURA et al
Serial No. 09/754,193
Filed: January 5, 2001

Group Art: 3723
Examiner: M. Rachuba
For: METHOD FOR POLISHING SURFACE OF
SEMICONDUCTOR DEVICE SUBSTRATE

PRELIMINARY AMENDMENT

Commissioner for Patents
Mail Stop Patent Application
Alexandria, VA 22313-1450

Sir:

Prior to examination, please amend the above-identified
application as follows.